

AMENDMENT TO THE CLAIMS:

This listing of claims will replace all prior versions of claims in the application:

LISTING OF CLAIMS:

1-16. (CANCELLED)

17. (CURRENTLY AMENDED) A method of making comprising the steps of:

making a read head including the steps of:

forming a read sensor;

forming first and second lead layers with the first and second lead layers connected to the read sensor;

forming nonmagnetic insulative first and second read gap layers with the read sensor and the first and second lead layers located between the first and second read gap layers;

forming ferromagnetic first and second shield layers with the first and second read gap layers located between the first and second shield layers and the first read gap layer having a resistance R_{G1} between the first shield layer and one of the first and second lead layers and the second read gap having a resistance R_{G2} between the second shield layer and said one of the first and second lead layers;

forming a connection via a plurality of resistors between a first node and each of the first and second shield layers wherein the plurality of resistors includes at least first and second resistors ~~R_{G1} and R_{G2}~~ R_{S1} and R_{S2} the first node is connected to said one of the first and second lead layers and a second node is located between the first and second resistors R_{S1} and R_{S2} and

SJO920000111US2/HIT1P162A

connecting first and second inputs of an operational amplifier to the first and second nodes respectively so as to be across the first resistor R_{S1} and connecting an output of the operational amplifier to the ~~first~~ second node for maintaining the first and second nodes at a common voltage potential.

18. (ORIGINAL) A method of making as claimed in claim 17 including making the sensor and the first and second resistances R_{S1} and R_{S2} coplanar.

19. (CURRENTLY AMENDED) A method of making as claimed in claim 18 wherein the step of making the sensor and the first and second resistances R_{S1} and R_{S2} coplanar includes the steps of:

~~simultaneously~~ simultaneously depositing a single layer of material for the sensor and the first and second resistances R_{S1} and R_{S2} and

simultaneously patterning said single layer of material to form the sensor and the first and second resistances R_{S1} and R_{S2} .

20. (ORIGINAL) A method of making as claimed in claim 17 including: connecting a first side of a test instrument for enabling a determination of resistance to the first node and connecting a second side of the test instrument to at least one of the first and second shield layers.

21. (ORIGINAL) A method of making as claimed in claim 20 including: shorting the first and second shield layers together; and connecting the second side of the test instrument to each of the first and second shield layers.

22. (ORIGINAL) A method of making as claimed in claim 21 including making the sensor and the first and second resistances R_{S1} and R_{S2} coplanar.

SJO920000111US2/HIT1P162A

23. (ORIGINAL) A method of making as claimed in claim 22 wherein a the step of making the sensor and the first and second resistances R_{S1} and R_{S2} coplanar includes the steps of:

simultaneously depositing a single layer of material for the sensor and the first and second resistances R_{S1} and R_{S2} and

simultaneously patterning said single layer of material to form the sensor and the first and second resistances R_{S1} and R_{S2} .

24. (ORIGINAL) A method of making as claimed in claim 23 further comprising the steps of:

making a write head including the steps of:

forming ferromagnetic first and second pole piece layers with a yoke portion between a pole tip portion and a back gap portion;

forming a nonmagnetic write gap layer between the pole tip portions of the first and second pole piece layers;

forming an insulation stack with at least one coil layer embedded therein located between the yoke portions of the first and second pole piece layers; and

connecting the first and second pole piece layers at their back gap portions.

25. (ORIGINAL) A method of making as claimed in claim 24 wherein the second shield layer and the first pole piece layer are formed as a common layer.

26. (ORIGINAL) A method of making as claimed in claim 24 wherein the second shield layer and the first pole piece layer are formed as separate layers; and

forming a nonmagnetic insulative isolation layer between the second shield layer and the first pole piece layer.

27. (ORIGINAL) A method of making as claimed in claim 17 including:

SJO920000111US2/HIT1P162A

the second resistor R_{S2} further being connected between the second node and the second shield layer; and

connecting a third resistor R_{S3} between the second node and the first shield layer.

28. (ORIGINAL) A method of making as claimed in claim 27 including making the sensor and the first, second and third resistances R_{S1} , R_{S2} and R_{S3} coplanar.

29. (ORIGINAL) A method of making as claimed in claim 28 wherein the step of making the sensor and the first, second and third resistances R_{S1} , R_{S2} and R_{S3} includes the steps of:

simultaneously depositing a single layer of material for the sensor and the first, second and third resistances R_{S1} , R_{S2} and R_{S3} and

simultaneously patterning said single layer of material to form the sensor and the first, second and third resistances R_{S1} , R_{S2} and R_{S3} .

30. (ORIGINAL) A method of making as claimed in claim 27 including: connecting a first side of a test instrument for enabling a determination of resistance to the first node and connecting a second side of the test instrument to the first shield layer.

31. (ORIGINAL) A method of making as claimed in claim 30 including making the sensor and the first, second and third resistances R_{S1} , R_{S2} and R_{S3} coplanar.

32. (ORIGINAL) A method of making as claimed in claim 31 wherein the step of making the sensor and the first, second and third resistances R_{S1} , R_{S2} and R_{S3} includes the steps of:

simultaneously depositing a single layer of material for the sensor and the first, second and third resistances R_{S1} , R_{S2} and R_{S3} and

SJO920000111US2/HIT1P162A

simultaneously patterning said single layer of material to form the sensor and the first, second and third resistances R_{S1} , R_{S2} and R_{S3} .

33. (ORIGINAL) A method of making as claimed in claim 32 wherein the second shield layer and the first pole piece layer are formed as a common layer.

34. (ORIGINAL) A method of making as claimed in claim 32 wherein the second shield layer and the first pole piece layer are formed as separate layers; and forming a nonmagnetic insulative isolation layer between the second shield layer and the first pole piece layer.

35. (ORIGINAL) A method of making as claimed in claim 27 including:

connecting a first side of a test instrument for enabling a determination of resistance to the first node and connecting a second side of the test instrument to the second shield layer.

36. (ORIGINAL) A method of making as claimed in claim 35 including making the sensor and the first, second and third resistances R_{S1} , R_{S2} and R_{S3} coplanar.

37. (CURRENTLY AMENDED) A method of making as claimed in claim 36 wherein the step of making the sensor and the first, second and third resistances R_{S1} , R_{S2} and R_{S3} includes the steps of:

~~simultaneously~~ simultaneously depositing a single layer of material for the sensor and the first, second and third resistances R_{S1} , R_{S2} and R_{S3} and simultaneously patterning said single layer of material to form the sensor and the first, second and third resistances R_{S1} , R_{S2} and R_{S3}

SJO920000111US2/HIT1P162A

38. (ORIGINAL) A method of as claimed in claim 37 wherein the second shield layer and the first pole piece layer are formed as a common layer.

39. (ORIGINAL) A method of making as claimed in claim 37 wherein the second shield layer and the first pole piece layer are formed as separate layers; and forming a nonmagnetic insulative isolation layer between the second shield layer and the first pole piece layer.

SJO920000111US2/HIT1P162A

- 7 -